

¢,

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: M. Landau
Yoshiyuki NAGAI et al.)	
	:	Group Art Unit: 2815
Application No.: 09/839,139)	
	:	Confirmation No.: 1616
Filed: April 23, 2001)	
	:	
For: LASER OSCILLATION APPARATUS, EXPOSURE)	April 14, 2004
APPARATUS, SEMICONDUCTOR DEVICE	:	
MANUFACTURING METHOD, SEMICONDUCTOR)	
MANUFACTURING FACTORY, AND EXPOSURE	:	
APPARATUS MAINTENANCE METHOD)	

Mail Stop Non-Fee Amendment

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Official Action dated January 14, 2004, please amend the aboveidentified application as follows: